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| U.S. Department of Commerce, Patent and Trademark Office | | | | Atty Docket No. | | Serial No. | |
| | | | | KUO-P102 | | Not yet assigned | |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT | | | | Applicant(s) | | | |
| (Use several sheets if necessary) | | | | Yee-Chung Fu, Chang-Li Hung | | | |
| | | | | Filing Date | | Group | |
| | | | | Herewith | | Not yet assigned | |
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| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date If Appropriate |
| | AA | 6,155,490 | 12/5/00 | Ackley | 235 | 472.01 | |
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| Foreign Patent Documents | | | | | | | |
| | | | | | | | Translation |
| | | Document | Date | Country | Class | Subclass | Yes No |
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| *EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant. | | | | | | | |

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| U.S. Department of Commerce, Patent and Trademark Office | | | | Atty Docket No. | | Serial No. | | |
| | | | | KUO-P100 | | Not yet assigned | | |
| INFORMATION DISCLOSURE STATEMENT BY APPLICANT | | | | Applicant(s) | | | | |
| (Use several sheets if necessary) | | | | Ting-Tung Kuo | | | | |
| | | | | Filing Date | | Group | | |
| | | | | Herewith | | Not yet assigned | | |
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